

## UNITED STATES PATENT AND TRADEMARK OFFICE

UNITED STATES DEPARTMENT OF COMMERCE United States Patent and Trademark Office Address: COMMISSIONER FOR PATENTS P.O. Box 1450 Alexandria, Virginia 22313-1450 www.uspto.gov

APPLICATION NO	Э.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/046,741		01/17/2002	Yoshinobu Ono	3885-0103P	2546	
2292	7590	03/18/2004		EXAMINER		
BIRCH S	TEWAR	T KOLASCH & BIF	MULPURI, SAVITRI			
PO BOX		VA 22040-0747	ART UNIT	PAPER NUMBER		
TALLO	noncii,	VII 22010 0717		2812		
				DATE MAILED: 03/18/200	4	

Please find below and/or attached an Office communication concerning this application or proceeding.

		<b>&amp;</b>			
	Appli	cation No.	Applicant(s)		
		46,741	ONO ET AL.		
Office Action Summary	Exam	niner	Art Unit		
		ri Mulpuri	2812		
The MAILING DATE of this comm Period for Reply	nunication appears of	n the cover sheet	with the correspondence address	s	
A SHORTENED STATUTORY PERIOR THE MAILING DATE OF THIS COMM!  Extensions of time may be available under the provis after SIX (6) MONTHS from the mailing date of this of If the period for reply specified above is less than this If NO period for reply is specified above, the maximu Failure to reply within the set or extended period for Any reply received by the Office later than three mor earned patent term adjustment. See 37 CFR 1.704(	UNICATION. ions of 37 CFR 1.136(a). In communication. ty (30) days, a reply within th m statutory period will apply a reply will, by statute, cause th ths after the mailing date of t	no event, however, may the statutory minimum of the and will expire SIX (6) Mo the application to become	a reply be timely filed  nirty (30) days will be considered timely.  DNTHS from the mailing date of this commur  ABANDONED (35 U.S.C. § 133).	nication.	
Status					
<ol> <li>Responsive to communication(s)</li> <li>This action is FINAL.</li> <li>Since this application is in condit closed in accordance with the present the present that the presen</li></ol>	2b)⊠ This action ion for allowance exc	is non-final. cept for formal ma		rits is	
Disposition of Claims					
4) ⊠ Claim(s) <u>5-14</u> is/are pending in the da) Of the above claim(s) 5) □ Claim(s) is/are allowed. 6) ⊠ Claim(s) <u>5-14</u> is/are rejected. 7) □ Claim(s) is/are objected to selected to reserve the day of	s/are withdrawn from				
Application Papers					
9) The specification is objected to by 10) The drawing(s) filed on is/s Applicant may not request that any of Replacement drawing sheet(s) inclu 11) The oath or declaration is objected	are: a) accepted objection to the drawing ding the correction is re	g(s) be held in abey equired if the drawir	ance. See 37 CFR 1.85(a). ng(s) is objected to. See 37 CFR 1.		
Priority under 35 U.S.C. § 119					
12) Acknowledgment is made of a cla a) All b) Some * c) None of 1. Certified copies of the prio 2. Certified copies of the prio 3. Copies of the certified cop application from the Intern * See the attached detailed Office a	f: rity documents have rity documents have ies of the priority doc ational Bureau (PCT	been received. been received in cuments have been Rule 17.2(a)).	Application No en received in this National Stag	ge	
Attachment(s)		A) 🗖 Intonúci	v Summary (PTO-413)		
<ol> <li>Notice of References Cited (PTO-892)</li> <li>Notice of Draftsperson's Patent Drawing Reviets</li> <li>Information Disclosure Statement(s) (PTO-144 Paper No(s)/Mail Date</li> </ol>		Paper N	o(s)/Mail Date f Informal Patent Application (PTO-152	)	

## **DETAILED ACTION**

A request for continued examination under 37 CFR 1.114, including the fee set forth in 37 CFR 1.17(e), was filed in this application after final rejection. Since this application is eligible for continued examination under 37 CFR 1.114, and the fee set forth in 37 CFR 1.17(e) has been timely paid, the finality of the previous Office action has been withdrawn pursuant to 37 CFR 1.114. Applicant's submission filed on 3/9/2004 has been entered.

## Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 5-14 are rejected under 35 U.S.C. 103(a) as being unpatentable over Admitted prior art in combination with Narui (publication from Journal of Crystal Growth).

Admitted prior art teaches a method of making a semiconductor device:

Providing a GaAs substrate; growing buffer GaAs layer; successively growing multiple

AlGaAs layers with first AlGaAs (aluminum content 0.4), second AlGaAs layer

(aluminum content 0.15) and third AlGaAs layer (aluminum content 0.4) and additional

GaAs. Admitted prior art teaches when AlGaAs layer having higher Al content is grown

on AlGAs having lower Al content, multi layer AlGaAs is prone to internal footballshaped abnormal growth and such problem is illustrated in fig.3. Admitted prior art

teaches all layers are grown on flat GaAs substrate as claimed in claims 5-14(see page 1, section (0006) and fig. 3).

Admitted prior art does not teach AlGaAs layer having high aluminum content is grown at lower growth rate than the growth rate of AlGaAs layer having lower aluminum content.

Admitted prior art does not teach growing AlGaAs having higher Al content at lower growth rate than the growth rate of AlGaAs having lower Al content.

Nauri teaches successively growing GaAs layer on GaAs substrate; growing plurality of AlGaAs layers with AlGaAs with Al content 0.45, AlGaAs with Al content 0.14, AlGaAs with Al content 0.45, AlGaAs with al content 0.45, AlGaAs aluminum content 0.45, wherein Al content grater than 0.4 is grown at a growth rate of 0.16 nm/sec. It would have been obvious to one of ordinary skill in the art to modify the invention of the admitted prior art by growing AlGaAs layers with higher Al content on AlGaAs with lower Al content at lower growth rate for the benefit of obtaining smooth surface.

## Response to Arguments

Applicant's arguments filed on 3/9/2004 have been fully considered but they are not persuasive. Applicant argues that Narui teaches growing AlGaAs on a ridge GaAs substrate as opposed to flat GaAs substrate as recited in instant invention. However Narui is relied on the teaching of AlGaAs with higher AlGaAs at slower growth rate 0.16 nm/sec to grow smooth AlGaAs layer and such growth results low threshold current without forming reflection coating (see conclusion section). Admitted prior art teaches

Art Unit: 2812

the sequence of the multilayer AlGaAs structure i.e., GaAs/AlGaAs heterostructure as instantly claimed sequence of layers and stresses that when AlGaAs with higher al content is grown on AlGaAs with lower Al content in AlGaAs multilayer structure results internal foot-ball shaped abnormal growth, which was depicted in figure.3. Modified invention, as modified by the teaching of AlGaAs having higher Al content by Narui, would give defect free AlGaAs multilayer structure, when AlGaAs grown at lower growth rate on flat GaAs substrate. Instant invention requires one only condition that AlGaAs with higher Al content is grown over flat GaAs substrate at lower growth rate. Whether the surface is flat or not, AlGaAs with higher Al content grown at lower growth rate would give smooth AlGaAs layer.

Applicant argues that the examiner turns to applicant's own disclosure for obviousness rejection. However, such argument is invalid because Admitted prior art as disclosed in background invention includes the problem of foot-ball shaped abnormal growth, when AlGaAs with higher Al content is grown on AlGaAs with lower Al content. Conclusively, modified invention of Admitted prior art would not have defects as was resulted by instant claimed process.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Savitri Mulpuri whose telephone number is 571-272-1677. The examiner can normally be reached on Mon-Fri from 7 to 4.30 p.m..

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, John Niebling, can be reached on 571-272-1679. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Application/Control Number: 10/046,741 Page 5

Art Unit: 2812

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Savitri Mulpuri Primary Examiner Art Unit 2812